

20. Microwave Engineering

Dec. 12, 2019

Microwave engineering

Microwave frequencies are a few GHz

The wavelength is smaller than the circuit

Losses in metals increase with increasing frequency

Losses in dielectrics increase with increasing frequency

There is a characteristic length scale called the skin depth which tells us how far into a metal fields penetrate before they are reflected out.

Skin depth $\omega\tau \ll 1$

$$\sigma(\omega) = ne\mu \left(\frac{1 - i\omega\tau}{1 + \omega^2\tau^2} \right) \approx ne\mu = \sigma_0 \quad \omega\tau \ll 1$$

Ohm's law $\vec{J} = \sigma_0 \vec{E}$

Take the curl $\frac{1}{\sigma_0} \nabla \times \vec{J} = \nabla \times \vec{E} = -\frac{d\vec{B}}{dt}$ Faraday's law

$\nabla \times \vec{B} = \mu_0 \vec{J}$ Ampere's law

$$\frac{1}{\sigma_0 \mu_0} \nabla \times \nabla \times \vec{B} = -\frac{d\vec{B}}{dt}$$

Vector identity $\nabla \times \nabla \times \vec{B} = \nabla(\nabla \cdot \vec{B}) - \nabla^2 \vec{B}$

$$\frac{1}{\sigma_0 \mu_0} \nabla^2 \vec{B} = \frac{d\vec{B}}{dt}$$

Skin depth

$$\frac{1}{\sigma_0 \mu_0} \nabla^2 \vec{B} = \frac{d\vec{B}}{dt}$$

Assume harmonic dependence $B_0 e^{i(kx - \omega t)}$

$$\frac{k^2}{\sigma_0 \mu_0} = i\omega$$

$$k = \sqrt{i\omega\sigma_0\mu_0} = \sqrt{\frac{\omega\sigma_0\mu_0}{2}} + i\sqrt{\frac{\omega\sigma_0\mu_0}{2}}$$

Skin depth $\delta = \sqrt{\frac{2}{\mu_0\sigma_0\omega}}$

Exponential decay



Light $\omega < \omega_p$ is reflected out of a metal. The waves penetrate a length δ .

Skin depth

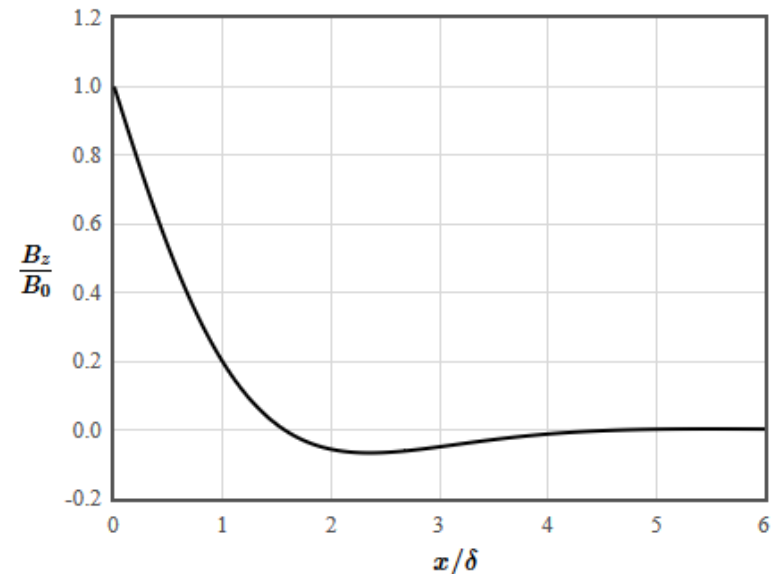
$$\vec{B} = B_0 e^{-x/\delta} e^{i(x/\delta - \omega t)} \hat{z}$$

$$\vec{J} = \frac{1}{\mu_0} \nabla \times \vec{B} = \vec{B} = \frac{B_0(1-i)}{\mu_0 \delta} e^{-x/\delta} e^{i(x/\delta - \omega t)} \hat{y}$$

$$1-i = \sqrt{2} e^{-i\pi/4}$$

$$\vec{J} = \frac{\sqrt{2} B_0}{\mu_0 \delta} e^{-x/\delta} e^{i(x/\delta - \omega t - \pi/4)} \hat{y}$$

$$\vec{E} = \frac{\vec{J}}{\sigma_0} = \frac{\sqrt{2} B_0}{\mu_0 \delta \sigma_0} e^{-x/\delta} e^{i(x/\delta - \omega t - \pi/4)} \hat{y}$$



The electric field lags behind the magnetic field by 45 degrees.

Surface resistance

At low frequencies:

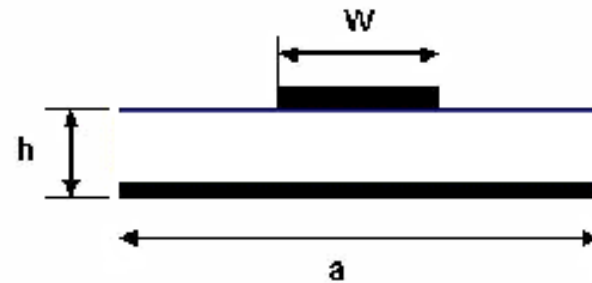
$$R = \frac{\rho \ell}{wt} = \frac{\ell}{\sigma_0 wt}$$

When $\delta < t$:

$$R = \frac{\ell}{\sigma_0 w \delta}$$

for $\ell = w$

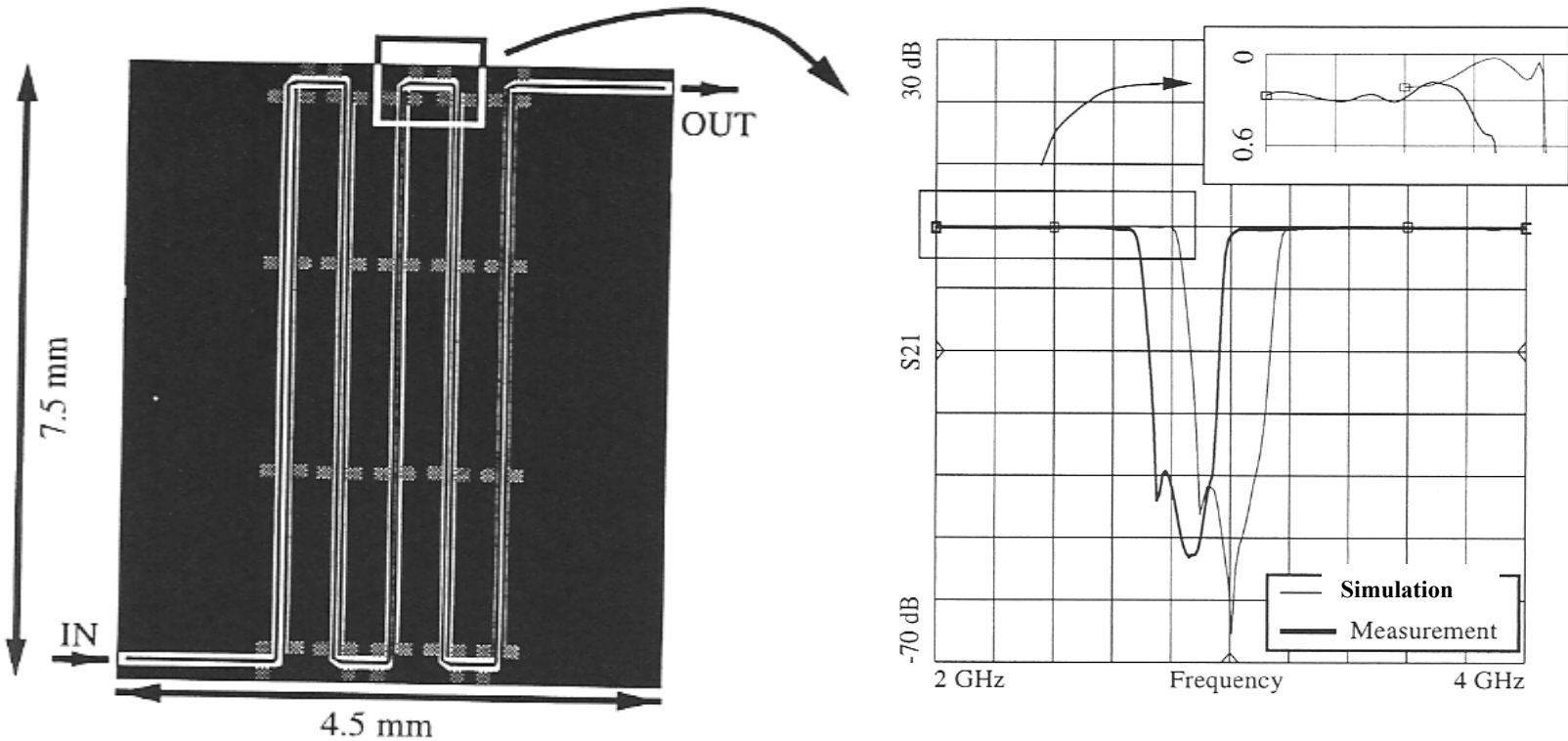
$$R_s = \frac{1}{\sigma_0 \delta} \propto \sqrt{\omega}$$



Complex signal processing at high frequencies > 1 GHz is difficult because the losses increase with frequency.

Usually you mix down to a lower frequency as soon as possible.

Superconducting filter



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Multiferroics

simultaneously ferroelectric and ferromagnetic



If two magnetic sublattices have different charge, changing the magnetic field can change the polarization and changing the electric field can change the magnetization.

Nitinol

Ni Ti alloy

Shape memory: If it is bent below a certain transition temperature and then heated above that temperature, it returns to its original shape.

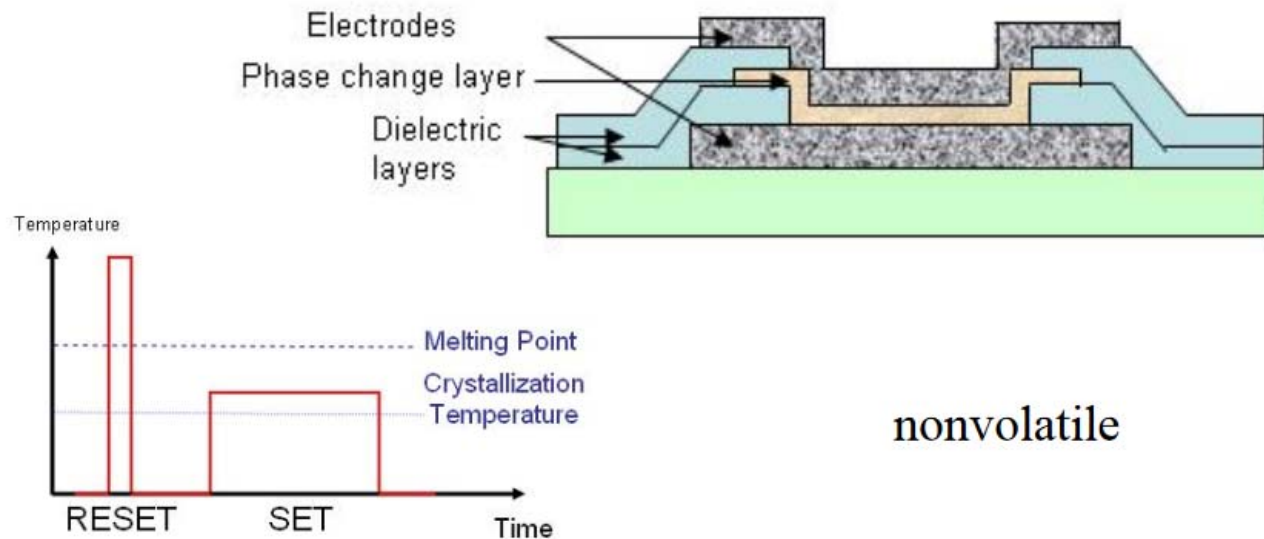
Superelasticity: Just above the transition temperature, the material exhibits elasticity 10-30 times that of an ordinary metal.

Martisite - Austinite

Phase change memory

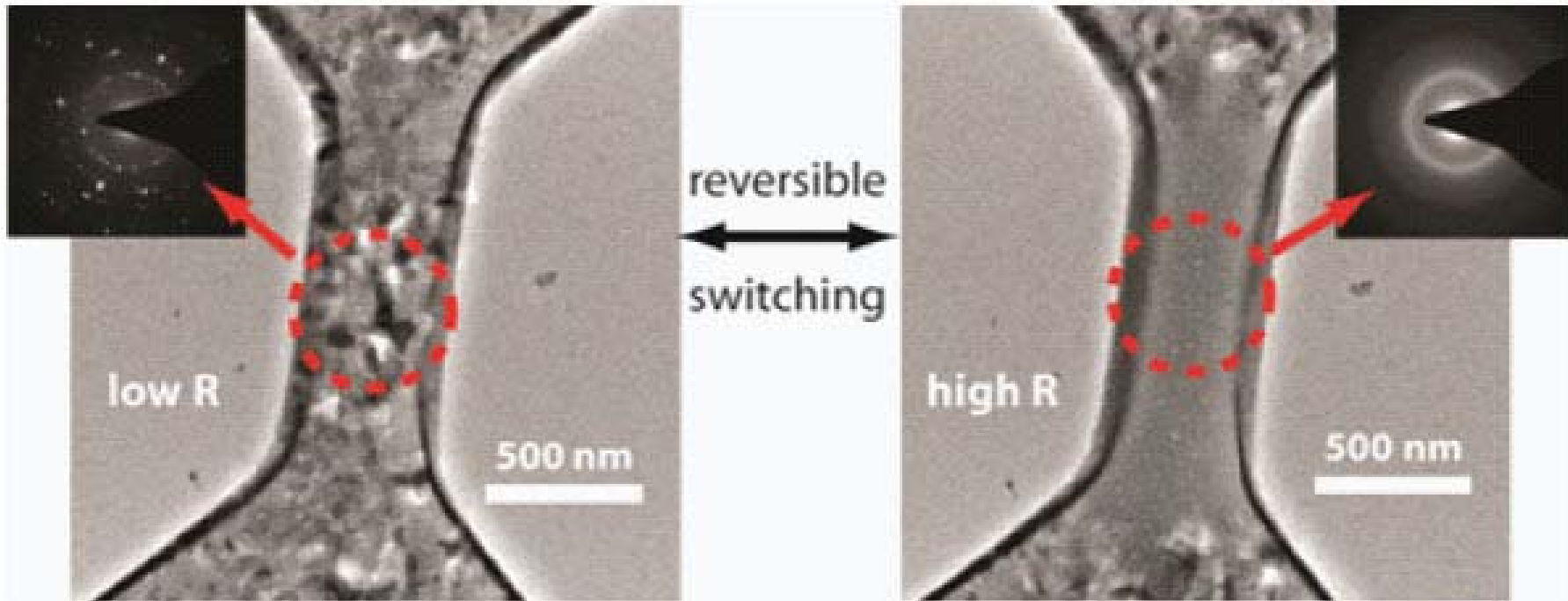
Phase-change memory (PRAM) uses chalcogenide materials. These can be switched between a low resistance crystalline state and a high resistance amorphous state.

GeSbTe is melted by a laser in rewritable DVDs and by a current in PRAM.



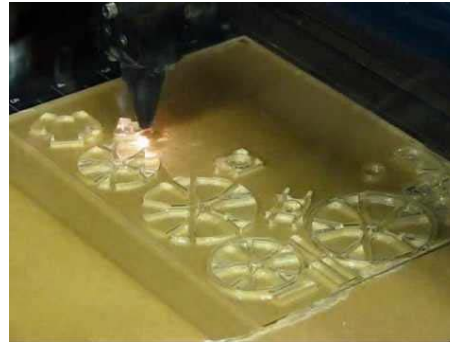
Phase change material

Electron diffraction in a TEM of a GeSbTe alloy.



http://web.stanford.edu/group/cui_group/research.htm

Laser-cutting/engraving

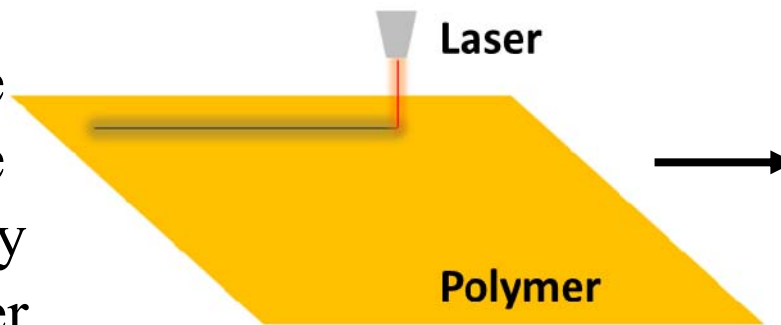


CUTTING AND/OR ENGRAVING of Plastic, Elastomers, Glass, Paper, Bio-derived materials, Metals, etc.

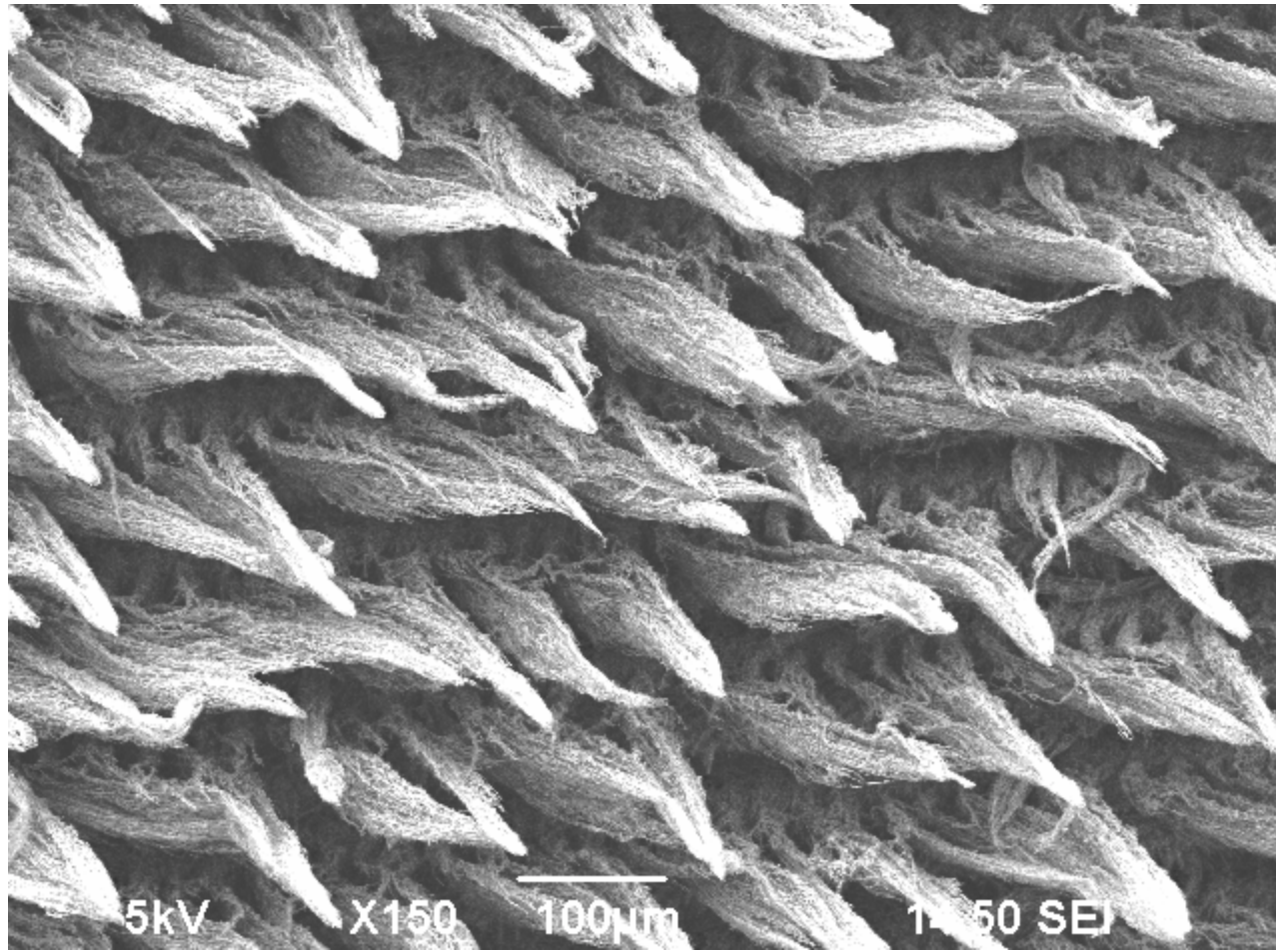
VLS 2.30 Universal Laser System

- laser source: 30 W CO₂ (wavelength 10.6 μm)
- equipped with: 2.0" lens (beam size at focus ~120 μm)
High Power Density Focusing Optics (beam size at focus ~30 μm)
- cutting table dimensions: 406 x 305 mm

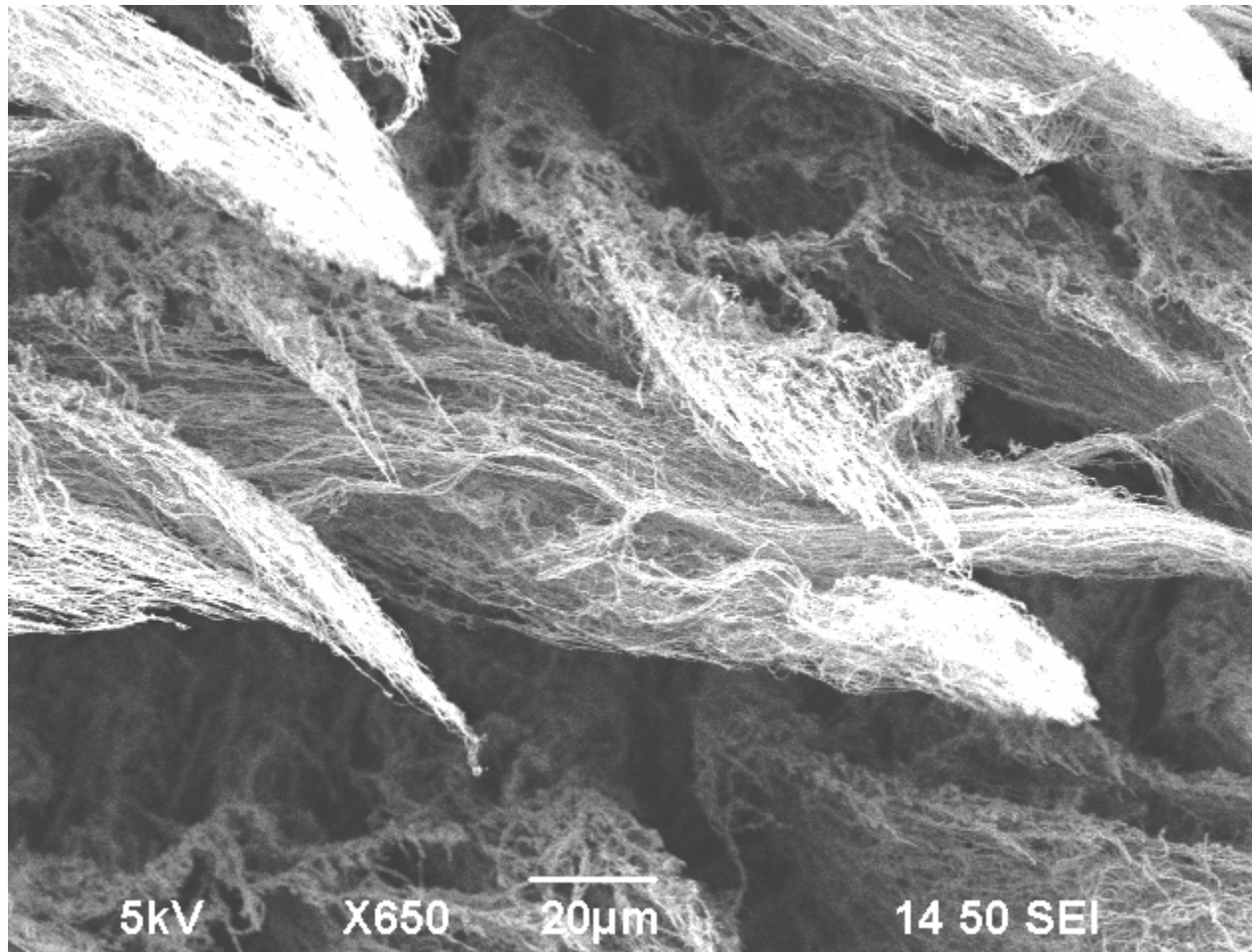
Patterning of conductive
Laser Induced Graphene
(photothermal process by
laser scribing on polymer)



laser-induced pyrolysis of polymers



laser-induced pyrolysis of polymers



laser-induced pyrolysis of polymers

